Amendments to the Specification

On page 5, paragraph 5:

These and other objects of the present invention are achieved in a photonic device with a silicon semiconductor based superlattice. The superlattice includes a plurality of layers that form a plurality of repeating units. At least one of the layers in the repeating unit is an optically active layer with at least one species of rare earth ion.

These and other objects of the present invention are achieved in a structure. The structure includes a silicon based superlattice with a plurality of layers that form a plurality of repeating units. At least one of the layers is an active region layer with at least one rare earth ion. At least a portion of the superlattice is made of substantially a Group III-V or II-VI material.

In another embodiment of the present invention, a structure is provided for efficient excitation or de-excitation mechanisms of a crystal field engineered rare-earth silicon-based superlattice. A silicon semiconductor based superlattice is provided that includes a plurality of layers which form a plurality of repeating units. At least one of the layers is an optically active layer with at least one species of rare earth ion. A first layer of semiconductor material is included. A second layer of semiconductor material is also provided. The superlattice is sandwiched between the first and second layers. The first and second layers each have a wider bandgap than the superlattice.

On page 24, after paragraph 3 and before paragraph 4:

In one embodiment of the present invention, a structure is provided includes a silicon based superlattice with a plurality of layers that form a plurality of repeating units. At least one of the layers is an active region layer with at least one rare earth ion. At least a portion of the superlattice is made of substantially a Group III-VI material.

In another embodiment of the present invention, a structure is provided for efficient excitation or de-excitation mechanisms of a crystal field engineered rare-earth silicon-based superlattice. A silicon semiconductor based superlattice is provided that includes a plurality of layers which form a plurality of repeating units. At least one of the layers is an optically active layer with at least one species of rare earth ion. A first layer of semiconductor material is included. A second layer of semiconductor material is also provided. The superlattice is sandwiched between the first and second layers. The first and second layers each have a wider bandgap than the superlattice.